Procedural Review Voting Sheet
2015 Cycle 1

REGION: China
COMMITTEE: PV
EVENT: SEMI China PV Standard TC Spring Meeting 2015
DATE OF MEETING: 2015/3/17
PLACE OF MEETING: Kerry Hotel, Shanghai, China
COMMITTEE CO-CHAIRS: Guangchun Zhang/ CSI, Jun Liu/CESI
SEMI STAFF: Kris Shen
A&R Voter: Name/Company
Date: 200X/MM/DD

I. Document Number & Title

Document 5727	Document Title New Standard: Test Method for the Etch Rate of a Crystalline Silicon Wafer by Determining the Weight Loss

II. Tally (Staff to fill in)

Voting Tally: As-cast tally after close of voting period

A minimum of 60% of the voting interests that have voting members within the technical committee must return votes. (Regulations ¶ 9.6.1)

	Return		Distribution		Return Rate	
Yellow	93	÷	154	=	60.4%	>=60%
Lilac & Others	83					
Total Vote	176					
Reject	0					
Accept	41					

A&R	☐ Not approved
	Reason:

III. Rejects

There was no reject submitted.

IV. Comments

Comment 1

Comment	Referenced Section	*TF/Committee to fill in if necessary
	From	Vargas-Beranl,Rafael (ITSdl)
	Comment	*In subsection 2.3, space between 'time' and '.' must be omitted. In addition, writing of introductory paragraph of the section 5 must be verified.*
	Discussion	None

Action proposed	X		**The committee agreed to do one of the following actions.**
			*No motion is required in this step.
			No further action was taken by the committee.
			Refer to the task force for more consideration.
			New Business
		X	Other
	Editorial Change		
			Case 1: No vote in this section :
			To be included and voted on in § 5. Summary of Editorial Changes.
		X	**Case 2: Voted in this section :**
			Original section number and at least one full sentence are required in "FROM" and "TO" fields.
		1	**FROM: Section 2.3** This standard specifies the corrosion time .
			To: Section 2.3 This standard specifies the corrosion time.
			Justification (If necessary)
		2	**FROM: Section 5.1** Choose the appropriate acid solution contact with silicon material samples for chemical etch,
			To: Section 5.1 5.1 Choose the appropriate acid solution contact with silicon material samples for chemical etch,
			Justification (If necessary)

Motion by/2nd	Fengxia Sun (Yingli)/Tongrong Zhao (JYT)
Vote	30-0 Motion passed
A&R	**Not approved**
	Reason:

Comment 2

Comment	**Referenced Section**	***TF/Committee to fill in if necessary**
	From	**Gan Yang (Harbin Institute of Technology)**
	Comment	*Strongly recommend polishing English carefully*
	Discussion	None

Action proposed	X	**The committee agreed to do one of the following actions.**	
		***No motion is required in this step.**	
			No further action was taken by the committee.
			Refer to the task force for more consideration.
			New Business
		X	Other
	Editorial Change		
			Case 1: No vote in this section :
			To be included and voted on in § 5. Summary of Editorial Changes.
		X	**Case 2: Voted in this section :**
			Original section number and at least one full sentence are required in "FROM" and "TO" fields.
		1	**FROM: Section 4.1.1** Crystalline Silicon Wafer Etch
			To: Section 4.1.1 crystalline silicon wafer etch
			Justification (If necessary)
		2	**FROM: Section 4.1.2** Edge Isolation Etch
			To: Section 4.1.2 edge isolation etch
			Justification (If necessary)
		3	**FROM: Section 4.1.3** Etch Rate

			To: Section 4.1.3 etch rate
			Justification (If necessary)
		4	**FROM: Section 4.1.4** Depth of Etch
			To: Section 4.1.4 depth of etch
			Justification (If necessary)

Motion by/2nd	Fengxia Sun (Yingli)/Tongrong Zhao (JYT)
Vote	30-0 Motion passed

A&R	**Not approved**
	Reason:

V. Summary of Editorial Changes

Note: Original section number and at least one full sentence are required in "FROM" and "TO" fields.

See editorial changes above.

VI. Approval Conditions Check

APPROVAL CONDITION 1: All negatives have been discussed and were withdrawn, found not related, or not persuasive. (Regulations ¶ 9.6.2)

APPROVAL CONDITION 2: At least 90% of the sum of the valid accept and reject votes must be accept. (Regulations ¶ 9.6.3)

Note: if both approval conditions are not satisfied, the document fails.

		Accepts		(Accepts + Valid			
Approval Rate	=	**41**	/	**41**	=	**100.0%**	**>=90%**

A&R	**Not approved**
	Reason:

VII. Safety Check

See § 14 of the Regulations for further information

Motion:	**X**	This is not a Safety Document: when all safety-related information is removed, the document is still technically sound and complete.	
		This is a Safety Document: when all safety-related information is removed, the document is not technically sound and complete.	
			Safety Checklist (Regulations ¶ 14.3) is complete and has been included with the document throughout the balloting process.
Motion by/2nd by			Fengxia Sun (Yingli)/Tongrong Zhao (JYT)
Discussion			None
Vote			30-0 Motion passed
A&R		**Not approved**	
		Reason:	

VIII. Intellectual Property Check

Note: This ballot may be all or part of a Standard or Safety Guideline. This IP check applies to the entire Standard or Safety Guideline. See § 15 of the Regulations for further information

X	The meeting chair asked those present in person or by electronic link, if they were aware of any potentially material patented technology or copyrighted items* in the Standard or Guideline.			
	X	No potentially material patented technology or copyrighted items are known		**GO TO SECTION IX**
		Potentially material patented technology or copyrighted items are known but a Letter of Assurance (LOA) or copyright release for such material has been obtained or presented to the committee.		**GO TO SECTION IX**
		Potentially material patented technology or copyrighted items are known but an LOA or copyright release for some of the material(s) has NOT been obtained or presented to the committee		
	MOTION		Ask ISC for special permission to publish	
			Quit activity	
			Wait for LOA for patented technology or release of copyrighted items.	
	Motion by/2nd by			
	Discussion			
	Vote			
	Final Action		Motion Passed	
			Motion Failed	
A&R			**Not approved**	
			Reason:	

* Note: Such potentially material patented technology or copyrighted items might have become known since the Standard or Safety Guideline was last reviewed, or might become relevant due to this ballot.

IX. Action for this document

Motion		This document passed committee review as balloted and will be forwarded to the A&R for procedural review.		
	X	This document passed committee review with editorial changes and will be forwarded to the A&R for procedural review.		
		This document failed committee review and will be returned to the task force for rework.		
		This document failed committee review and work will be discontinued.		
Motion by/2nd by		Fengxia Sun (Yingli)/Tongrong Zhao (JYT)		
Discussion		None		
Vote		30-0 Motion passed		
Final Action		X	Motion passed	
			Motion failed	
A&R		**Approved**		
		Not approved		

	Reason: